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INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

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Complete if Known	
Application No.	10/566,849
Filing Date	May 9, 2006
First Named Inventor	Karl-Heinz Schuster
Art Unit	2851
Examiner Name	Steve Whitesell
Attorney Docket No.	SHN-146-A

U.S. Patent Documents				
INITIALS	Cite No. ¹	Document No.	Publication Date mm-dd-yyyy	Name of Patentee or Applicant of Cited Document
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	XP-00223300789 "WATER-BASED 193nm IMMERSION LITHOGRAPHY" Online!, Bruce Smith, 28 January 2004 (2004-01-28), XP 002329291 retrieved from the Internet: URL: http://www.sematech.org/resources/litho/meetings/immersion/20040128/presentations/06%20ri%20\$microstepper%20efforts_Smith.pdf retrieved on 2005-05-24, p. 14: NA>1.0ns material: SiO2, p. 22: n(liquid lens)>1.6>n(SiO2)

/Steven Whitesell, CTO

DATE CONSIDERED

07/01/2006

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not considered. Include a copy of this form with next communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /S.W./